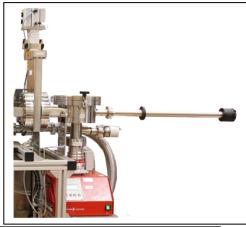


Substrate Mount Assemblies, Manipulation and Loadlock Systems

Substrate mount design influences film uniformity and characteristics. Your application will determine which features are important. Our substrate mount assemblies may incorporate the following features:

Feature	Issues and Options
Sample size	 Standard sizes: circular diameter 2"- 8" Non-standard sizes: Structures are designed to fix samples of any size or shape.
Heating	 Resistive heating element (tungsten, SiC or other): up to above 850 °C Quartz halogen lamps Temperature measurement with PID control integrated into system software
Cooling	 May be required to prevent overheating of temperature-sensitive materials Cooling lines integrated into substrate mount Chilled fluid, closed or open cycle
Biasing	 RF, DC and Pulsed-DC High voltage DC and Pulsed-DC for ion implantation – up to 10 kV
Axial motion (translation)	 Adjust source-substrate distance to optimise deposition rate and film quality Bellows-sealed translating stage (UHV compatible) Manual or Motorised with interface to process control software Sliding o-ring seal (adjustable only when chamber is vented)
Rotation	 Motorised, adjustable speed up to 20 rpm and interfaced to control software
Shutters and Masking	 Shutters for shielding the sample (manual or automated), Integration into control software Shadow mask positioning systems







Note that some combinations are not available. Please <u>inquire</u> with your specific requirements.

Load-lock Systems

Plasmionique can provide load-lock systems incorporating:

- Stainless steel vacuum chamber with large access door
- Turbomolecular pumping package (dry) with manual or pneumatic gate valve for isolation
- Vacuum gauge
- Magnetically-coupled transfer arm with sample transfer mechanism